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2598/1G196US1

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Sang Kyeong YUN and Dong Hoon KIM

Filed: CONCURRENTLY .

NAME (PRINT)

For: PIEZOELECTRIC/ELECTROSTRICTIVE FILM ELEMENT-FORMED AT LOW

TEMPERATURE USING ELECTROPHORETIC DEPOSITION

## **PRELIMINARY AMENDMENT**

Hon. Commissioner of Patents and Trademarks Washington, DC 20231

Sir:

Prior to examining the above-identified patent application, please enter the following amendment(s):

In the Claims:

## Please amend Claims 22 and 41 to read as follows:

21, wherein the method further comprises a step of drying said piezoelectric/electrostrictive film between g) and h).

(Amended) The piezoelectric/electrostrictive film element in Claim

A